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August 3, 2006

Julie Goldberg  
Nanometrics Incorporated  
1550 Buckeye Drive  
Milpitas, CA 95035-7418

Re: U.S. Patent Application: "Method for Automatically De-Skewing of Multiple  
Layer Wafer for Improved Pattern Recognition"  
Inventors: Jian Zhou et al.  
Serial No.: 09/974,721  
Filing Date: October 9, 2001  
Our Reference: NAN050 US

**FOR YOUR FILES**

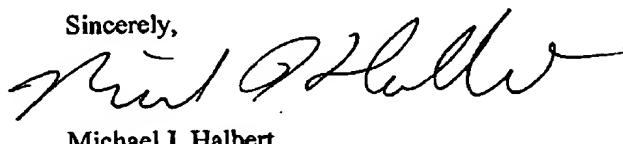
Dear Julie:

Enclosed for your files are copies of the following:

1. Request for Continued Examination (RCE) Transmittal; and
2. Response to Office Action.

These materials were mailed via Facsimile to the United States Patent and Trademark  
Office on August 3, 2006. Please let me know if there are any questions or comments.

Sincerely,



Michael J. Halbert

MJH/mh  
Enclosures